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# Scanning Probe Microscopy

Atomic Force Microscopy and  
Scanning Tunneling Microscopy

# Contents

<b>1</b>	<b>Introduction . . . . .</b>	<b>1</b>
1.1	Introduction to Scanning Tunneling Microscopy . . . . .	4
1.2	Introduction to Atomic Force Microscopy . . . . .	7
1.3	A Short History of Scanning Probe Microscopy . . . . .	10
1.4	Summary . . . . .	11

## Part I Scanning Probe Microscopy Instrumentation

<b>2</b>	<b>Harmonic Oscillator . . . . .</b>	<b>15</b>
2.1	Free Harmonic Oscillator . . . . .	15
2.2	Driven Harmonic Oscillator . . . . .	17
2.3	Driven Harmonic Oscillator with Damping . . . . .	19
2.4	Transients of Oscillations . . . . .	23
2.5	Dissipation and Quality Factor of a Damped Driven Harmonic Oscillator . . . . .	25
2.6	Effective Mass of a Harmonic Oscillator . . . . .	26
2.7	Linear Differential Equations . . . . .	28
2.8	Summary . . . . .	29
<b>3</b>	<b>Technical Aspects of Scanning Probe Microscopy . . . . .</b>	<b>31</b>
3.1	Piezoelectric Effect . . . . .	31
3.2	Extensions of Piezoelectric Actuators . . . . .	34
3.3	Piezoelectric Materials . . . . .	37
3.4	Tube Piezo Element . . . . .	39
3.4.1	Resonance Frequencies of Piezo Tubes . . . . .	43
3.5	Flexure-Guided Piezo Nanopositioning Stages . . . . .	45
3.6	Non-linearities and Hysteresis Effects of Piezoelectric Actuators . . . . .	46
3.6.1	Hysteresis . . . . .	46
3.6.2	Creep . . . . .	49

3.6.3	Thermal Drift . . . . .	50
3.7	STM Tip Preparation . . . . .	50
3.8	Vibration Isolation . . . . .	52
3.8.1	Isolation of the Microscope from Outer Vibrations . . . . .	52
3.8.2	The Microscope Considered as a Vibrating System . . . . .	56
3.8.3	Combining Vibration Isolation and a Microscope with High Resonance Frequency . . . . .	58
3.9	Building Vibrations . . . . .	61
3.10	Summary . . . . .	63
<b>4</b>	<b>Scanning Probe Microscopy Designs . . . . .</b>	<b>65</b>
4.1	Nanoscope . . . . .	65
4.2	Inertial Sliders . . . . .	66
4.3	Beetle STM . . . . .	71
4.4	Pan Slider . . . . .	72
4.5	KoalaDrive . . . . .	73
4.6	Tip Exchange . . . . .	75
4.7	Summary . . . . .	75
<b>5</b>	<b>Electronics for Scanning Probe Microscopy . . . . .</b>	<b>77</b>
5.1	Voltage Divider . . . . .	77
5.2	Impedance, Transfer Function, and Bode Plot . . . . .	78
5.3	Output Resistance/Input Resistance . . . . .	80
5.4	Noise . . . . .	81
5.5	Operational Amplifiers . . . . .	82
5.5.1	Voltage Follower/Impedance Converter . . . . .	83
5.5.2	Voltage Amplifier . . . . .	84
5.6	Current Amplifier . . . . .	86
5.7	Feedback Controller . . . . .	88
5.7.1	Proportional Controller . . . . .	89
5.7.2	Proportional-Integral Controller . . . . .	90
5.8	Feedback Controller in STM . . . . .	91
5.9	Implementation of an STM Feedback Controller . . . . .	94
5.10	Digital-to-Analog Converter . . . . .	96
5.11	Analog-to-Digital Converter . . . . .	97
5.12	High-Voltage Amplifier . . . . .	98
5.13	Summary . . . . .	99

<b>6</b>	<b>Lock-In Technique . . . . .</b>	101
6.1	Lock-In Amplifier—Principle of Operation. . . . .	101
6.2	Summary . . . . .	105
<b>7</b>	<b>Data Representation and Image Processing . . . . .</b>	107
7.1	Data Representation. . . . .	107
7.2	Image Processing . . . . .	112
7.3	Data Analysis . . . . .	113
7.4	Summary . . . . .	114
<b>8</b>	<b>Artifacts in SPM . . . . .</b>	115
8.1	Tip-Related Artifacts . . . . .	115
8.2	Other Artifacts . . . . .	119
8.3	Summary . . . . .	121
<b>9</b>	<b>Work Function, Contact Potential, and Kelvin Probe Scanning Force Microscopy . . . . .</b>	123
9.1	Work Function . . . . .	123
9.2	Effect of a Surface on the Work Function . . . . .	124
9.3	Surface Charges and External Electric Fields . . . . .	126
9.4	Contact Potential. . . . .	129
9.5	Measurement of Work Function by the Kelvin Method . . . . .	129
9.6	Kelvin Probe Scanning Force Microscopy (KFM) . . . . .	131
9.7	Summary . . . . .	132
<b>10</b>	<b>Surface States . . . . .</b>	135
10.1	Surface States in a One-Dimensional Crystal . . . . .	135
10.2	Surface States in 3D Crystals . . . . .	139
10.3	Surface States Within the Tight Binding Model . . . . .	140
10.4	Summary . . . . .	141

## Part II Atomic Force Microscopy (AFM)

<b>11</b>	<b>Forces Between Tip and Sample . . . . .</b>	145
11.1	Tip-Sample Forces . . . . .	145
11.2	Snap-to-Contact . . . . .	149
11.3	Summary . . . . .	155
<b>12</b>	<b>Technical Aspects of Atomic Force Microscopy (AFM) . . . . .</b>	157
12.1	Requirements for Force Sensors . . . . .	157
12.2	Fabrication of Cantilevers. . . . .	159
12.3	Beam Deflection Atomic Force Microscopy . . . . .	161

12.3.1	Sensitivity of the Beam Deflection Method . . . . .	162
12.3.2	Detection Limit of the Beam Deflection Method . . . . .	164
12.4	Other Detection Methods . . . . .	165
12.5	Calibration of AFM Measurements . . . . .	167
12.5.1	Experimental Determination of the Sensitivity Factor in AFM . . . . .	167
12.5.2	Calculation of the Spring Constant from the Geometrical Data of the Cantilever . . . . .	168
12.5.3	Sader Method for the Determination of the Spring Constant of a Cantilever . . . . .	170
12.5.4	Thermal Method for the Determination of the Spring Constant of a Cantilever . . . . .	170
12.5.5	Experimental Determination of the Sensitivity and Spring Constant in AFM Without Tip-Sample Contact . . . . .	174
12.6	Summary . . . . .	175
<b>13</b>	<b>Static Atomic Force Microscopy . . . . .</b>	<b>177</b>
13.1	Principles of Static Atomic Force Microscopy. . . . .	177
13.2	Properties of Static AFM Imaging. . . . .	179
13.3	Constant Height Mode in Static AFM . . . . .	180
13.4	Friction Force Microscopy (FFM) . . . . .	181
13.5	Force-Distance Curves. . . . .	182
13.6	Summary . . . . .	186
<b>14</b>	<b>Amplitude Modulation (AM) Mode in Dynamic Atomic Force Microscopy . . . . .</b>	<b>187</b>
14.1	Parameters of Dynamic Atomic Force Microscopy . . . . .	187
14.2	Principles of Dynamic Atomic Force Microscopy I (Amplitude Modulation). . . . .	188
14.3	Amplitude Modulation (AM) Detection Scheme in Dynamic Atomic Force Microscopy. . . . .	193
14.4	Experimental Realization of the AM Detection Mode . . . . .	196
14.5	Time Constant in AM Detection . . . . .	198
14.6	Dissipative Interactions in Non-contact AFM in the Small Amplitude Limit . . . . .	200
14.7	Dependence of the Phase on the Damping and on the Force Gradient. . . . .	203
14.8	Summary . . . . .	204

<b>15 Intermittent Contact Mode/Tapping Mode . . . . .</b>	205
15.1 Atomic Force Microscopy with Large Oscillation Amplitudes . . . . .	205
15.2 Resonance Curve for an Anharmonic Force-Distance Dependence . . . . .	211
15.3 Amplitude Instabilities for an Anharmonic Oscillator . . . . .	213
15.4 Energy Dissipation in Dynamic Atomic Force Microscopy . . . . .	217
15.5 Properties of the Intermittent Contact Mode/Tapping Mode . . . . .	220
15.6 Summary . . . . .	221
<b>16 Mapping of Mechanical Properties Using Force-Distance Curves . . . . .</b>	223
16.1 Principles of Force-Distance Curve Mapping . . . . .	223
16.2 Mapping of the Mechanical Properties of the Sample . . . . .	226
16.3 Summary . . . . .	227
<b>17 Frequency Modulation (FM) Mode in Dynamic Atomic Force Microscopy—Non-contact Atomic Force Microscopy . . . . .</b>	229
17.1 Principles of Dynamic Atomic Force Microscopy II . . . . .	229
17.1.1 Expression for the Frequency Shift . . . . .	232
17.1.2 Normalized Frequency Shift in the Large Amplitude Limit . . . . .	235
17.1.3 Recovery of the Tip-Sample Force . . . . .	238
17.2 Experimental Realization of the FM Detection Scheme . . . . .	238
17.2.1 Self-excitation Mode . . . . .	238
17.2.2 Frequency Detection with a Phase-Locked Loop (PLL) . . . . .	244
17.2.3 PLL Tracking Mode . . . . .	248
17.3 The Non-monotonous Frequency Shift in AFM . . . . .	250
17.4 Comparison of Different AFM Modes . . . . .	251
17.5 Summary . . . . .	252
<b>18 Noise in Atomic Force Microscopy . . . . .</b>	255
18.1 Thermal Noise Density of a Harmonic Oscillator . . . . .	255
18.2 Thermal Noise in the Static AFM Mode . . . . .	258
18.3 Thermal Noise in the Dynamic AFM Mode with AM Detection . . . . .	258
18.4 Thermal Noise in Dynamic AFM with FM Detection . . . . .	260
18.5 Sensor Displacement Noise in the FM Detection Mode . . . . .	262
18.6 Total Noise in the FM Detection Mode . . . . .	263
18.7 Comparison to Noise in STM . . . . .	264
18.8 Signal-to-Noise Ratio in Atomic Force Microscopy FM Detection . . . . .	265
18.9 Summary . . . . .	267

<b>19</b>	<b>Quartz Sensors in Atomic Force Microscopy . . . . .</b>	<b>269</b>
19.1	Tuning Fork Quartz Sensor . . . . .	269
19.2	Quartz Needle Sensor . . . . .	270
19.3	Determination of the Sensitivity of Quartz Sensors . . . . .	273
19.4	Summary . . . . .	275

## Part III Scanning Tunneling Microscopy and Spectroscopy

<b>20</b>	<b>Scanning Tunneling Microscopy . . . . .</b>	<b>279</b>
20.1	One-Dimensional Potential Barrier Model . . . . .	279
20.2	Flux of Matter and Charge in Quantum Mechanics . . . . .	284
20.3	The WKB Approximation for Tunneling . . . . .	286
20.4	Density of States. . . . .	288
20.5	Bardeen Model for Tunneling. . . . .	289
	20.5.1 Energy-Dependent Approximation of the Bardeen Model . . . . .	292
	20.5.2 Tersoff-Hamann Approximation of the Bardeen Model . . . . .	300
20.6	Constant Current Mode and Constant Height Mode. . . . .	302
20.7	Voltage-Dependent Imaging . . . . .	304
20.8	Summary . . . . .	306
<b>21</b>	<b>Scanning Tunneling Spectroscopy (STS) . . . . .</b>	<b>309</b>
21.1	Scanning Tunneling Spectroscopy—Overview . . . . .	309
21.2	Experimental Realization of Spectroscopy with STM. . . . .	310
21.3	Normalized Differential Conductance. . . . .	313
21.4	Relation Between Differential Conductance and the Density of States . . . . .	316
21.5	Recovery of the Density of States . . . . .	319
21.6	Asymmetry in the Tunneling Spectra . . . . .	322
21.7	Beyond the 1D Barrier Approximation. . . . .	324
21.8	Energy Resolution in Scanning Tunneling Spectroscopy. . . . .	324
21.9	Barrier Height Spectroscopy . . . . .	327
21.10	Barrier Resonances . . . . .	329
21.11	Spectroscopic Imaging . . . . .	330
	21.11.1 Example: Spectroscopy of the Si( $7 \times 7$ ) Surface . . . . .	330
21.12	Summary . . . . .	333

<b>22</b>	<b>Vibrational Spectroscopy with the STM . . . . .</b>	335
22.1	Principles of Inelastic Tunneling Spectroscopy with the STM . . . . .	335
22.2	Examples of Vibrational Spectra Obtained with the STM . . . . .	337
22.3	Summary . . . . .	340
<b>23</b>	<b>Spectroscopy and Imaging of Surface States . . . . .</b>	341
23.1	Energy Dependence of the Density of States in Two, One and Zero Dimensions . . . . .	341
23.2	Scattering of Surface State Electrons at Surface Defects . . . . .	345
23.3	Summary . . . . .	347
<b>24</b>	<b>Building Nanostructures Atom by Atom . . . . .</b>	349
24.1	Positioning of Single Atoms and Molecules by STM . . . . .	349
24.2	Electron Confinement in Nanoscale Cages . . . . .	354
24.3	Inducing a Single Molecule Chemical Reaction with the STM Tip . . . . .	356
24.4	Summary . . . . .	357
<b>Appendix A: Horizontal Piezo Constant for a Tube Piezo Element . . . . .</b>		359
<b>Appendix B: Fermi's Golden Rule and Bardeen's Matrix Elements . . . . .</b>		363
<b>Appendix C: Frequency Noise in FM Detection . . . . .</b>		371
<b>References . . . . .</b>		375
<b>Index . . . . .</b>		377